Art Unit: 2815

Examiner: Mr. William F. Kraig

In re PATENT APPLICATION of:

•	Akira TAKAHASHI	·) .
:	10/798,482	.)
:	March 12, 2004) <u>AMENDMENT</u>
:	DRY ETCHING METHOD FOR SEMICONDUCTOR DEVICE)
:	OKI 414) March 24, 2008
	:	 : 10/798,482 : March 12, 2004 : DRY ETCHING METHOD FOR SEMICONDUCTOR DEVICE

Mail Stop Amendment

Director of Patents P.O. Box 1450 Alexandria, VA 22313-1450

Sir:

This is responsive to the Office Action of October 22, 2007, the period for reply to which is being extended to expire on March 22, 2008 (a Saturday, and thus on the following Monday, March 24, 2008) by a Petition that is being filed concurrently.

A fee of \$\frac{460}{160}\] is also being submitted concurrently. Should this remittance be accidentally missing, however, or should any additional fees be needed, the Director may charge such fees to our Deposit Account number 18-0002.

Please amend the above-identified application as specified on the following pages, and then reconsider the application in view of the Remarks that are presented thereafter.